

L Number	Hits	Search Text	DB	Time stamp
1	3	inspect\$3 near9 (wafer) and aligner and cutout	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:30
2	1		USPAT	2004/06/08 15:14
3	1		USPAT	2004/06/08 15:15
4	28	Akamatsu near Takahiro	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:25
5	14	yoshimoto near akito	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:26
6	21	takayasu near yamamoto	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:28
7	1	tatefumi near oda	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:28
8	0	inspect\$3 near9 (wafer) and detect\$3 near9 (center and cutout)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:30
9	2	detect\$3 near9 ((center and cutout) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:30
10	2	(inspect\$3 or detect\$3) near9 ((center and cutout) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:32
11	71	(inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:33
12	6	((inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)) and inspect\$3 near device	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:39
13	1	"04290455"	JPO	2004/06/08 15:39
14	35	((inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)) and inspect\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:39

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7	1	tatefumi near oda	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:28
8	0	inspect\$3 near9 (wafer) and detect\$3 near9 (center and cutout)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:30
9	2	detect\$3 near9 ((center and cutout) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:30
10	2	(inspect\$3 or detect\$3) near9 ((center and cutout) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:32
11	71	(inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:33
12	6	((inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)) and inspect\$3 near device	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:39
13	1	"04290455"	JPO	2004/06/08 15:39
14	35	((inspect\$3 or detect\$3) near9 ((center and notch) near5 wafer)) and inspect\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:52

15	46	aligner near6 ((light near source) and (sensor or detect\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:53
16	2	(aligner near6 ((light near source) and (sensor or detect\$3))) and inspect\$3 near15 wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:54
17	0	(aligner near6 ((light near source) and (sensor or detect\$3))) and inspect\$3 near9 noth	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:55
18	0	(aligner near6 ((light near source) and (sensor or detect\$3))) and inspect\$3 and noth	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:55
19	0	(aligner near6 ((light near source) and (sensor or detect\$3))) and inspect\$3 near9 notch	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:55
20	0	(aligner near6 ((light near source) and (sensor or detect\$3))) and inspect\$3 and notch	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/06/08 15:55